



Recent Advances in Micro/Nano Flexible Sensors

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Message from the Guest Editors

Dear Colleagues,

Flexible sensors are electronic devices which can sense various physical parameters, such as pressure/strain, temperature, gas, and so on. These devices have the characteristics of conformability, lightweight, and have a low cost, showing their application potential in the field of sensing and measurement, such as human health monitoring, robotics, wearable electronics, artificial intelligence, etc. However, flexible sensors still face the several barriers toward high-level performance and industrialization. The major challenges are reliability and the balance between electrical and mechanical properties. This Special Issue “Recent Advances in Micro/Nano Flexible Sensors” calls for full-size research papers and reviews on flexible sensors designs (include materials, structures, etc.) and their innovative application.

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Guest Editors





Editor-in-Chief

Message from the Editor-in-Chief

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